

ABSTRACT OF THE DISCLOSURE

SYSTEM AND METHOD FOR AUTOMATING USER INTERACTION FOR SEMICONDUCTOR MANUFACTURING EQUIPMENT

A system includes an interface and a controller. The interface is configured to receive a state a substrate processing tool comprising a plurality of process modules configured to process a substrate. The controller is configured to correlate the state with an input previously received by the substrate processing tool from the interface based on the state and to generate an output to control the substrate processing tool based on the correlation.

Figure 7